

Low Temperature Ion Beam Sputter Coatings

Dr. Thomas Gischkat

Project Manager Optical Coatings @ RhySearch

- Optical functionality require proper coating design and thin film properties, e.g. laser applications:
 - low optical losses (ppm)
 - high laser damage resistance

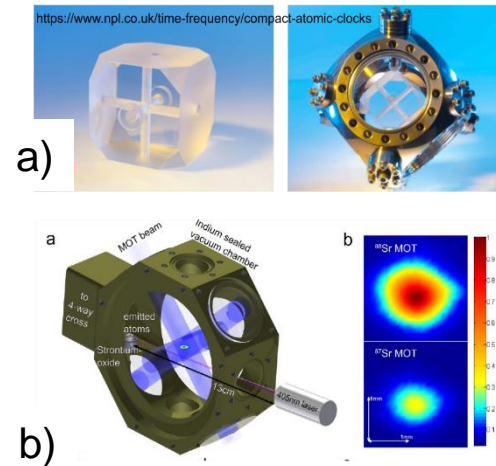


Fig.: Atomic clocks design.

a) O. Koc, W. He, D. Swierad, L. Smith, J. Hughes, K. Bong, and Y. Singh, *Laser controlled atom source for optical clocks*, Sci. Rep., 6 (2016) 37321.

b) <https://www.npl.co.uk/time-frequency/compact-atomic-clocks>

- Optical functionality require proper coating design and thin film properties, e.g. laser applications:
 - low optical losses (ppm)
 - high laser damage resistance
- Temperature sensitive substrates and processes, e.g. polymers or cemented components require:
 - Temp. $\ll 100^{\circ}\text{C}$

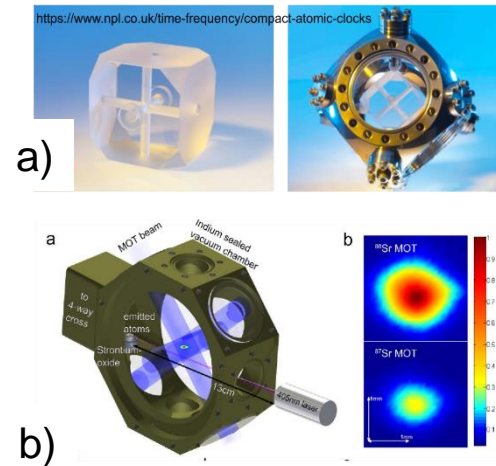


Fig.: Atomic clocks design.

a) O. Koc, W. He, D. Swierad, L. Smith, J. Hughes, K. Bong, and Y. Singh, *Laser controlled atom source for optical clocks*, Sci. Rep., 6 (2016) 37321.

b) <https://www.npl.co.uk/time-frequency/compact-atomic-clocks>

- Optical functionality require proper coating design and thin film properties, e.g. laser applications:
 - low optical losses (ppm)
 - high laser damage resistance
- Temperature sensitive substrates and processes, e.g. polymers or cemented components require:
 - Temp. $\ll 100^\circ\text{C}$
- Thin film properties depending on:
 - Coating technology (energy)
 - Deposition parameters, e.g. temperature

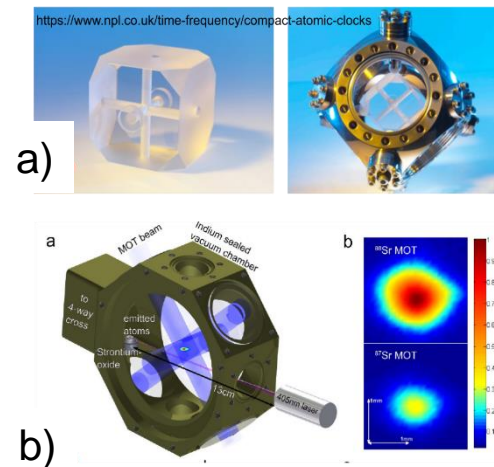


Fig.: Atomic clocks design.

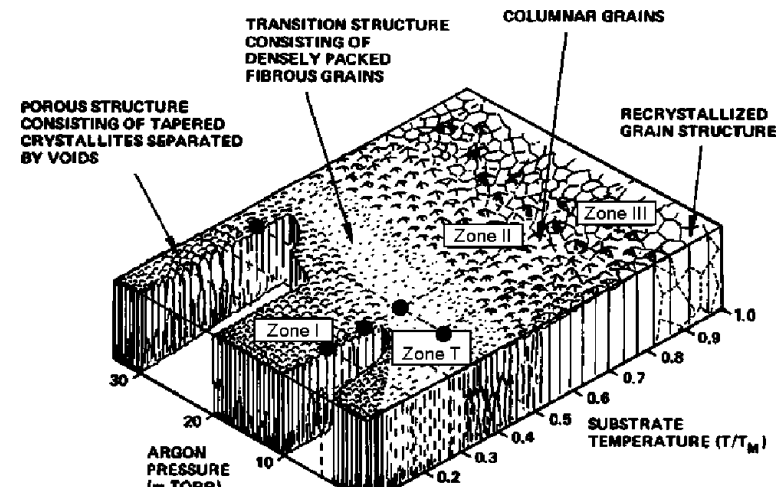


Fig.: Thornton structure zone model.

- Optical functionality require proper coating design and thin film properties, e.g. laser applications:
 - low optical losses (ppm)
 - high laser damage resistance
- Temperature sensitive substrates and processes, e.g. polymers or cemented components require:
 - Temp. $\ll 100^\circ\text{C}$
- Thin film properties depending on:
 - Coating technology (energy)
 - Deposition parameters, e.g. temperature
- Standard: $T_{\text{coating}} \geq 100^\circ\text{C}$
 - Active cooling required for deposition below $T_{\text{coating}} \ll 100^\circ\text{C}$
 - Investigations on thin film properties as a function of $T_{\text{coating}} \ll 100^\circ\text{C}$

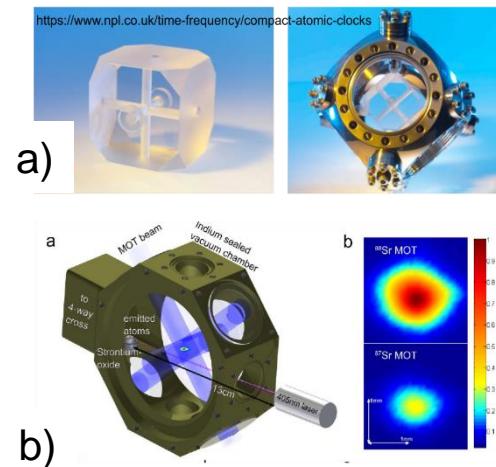


Fig.: Atomic clocks design.

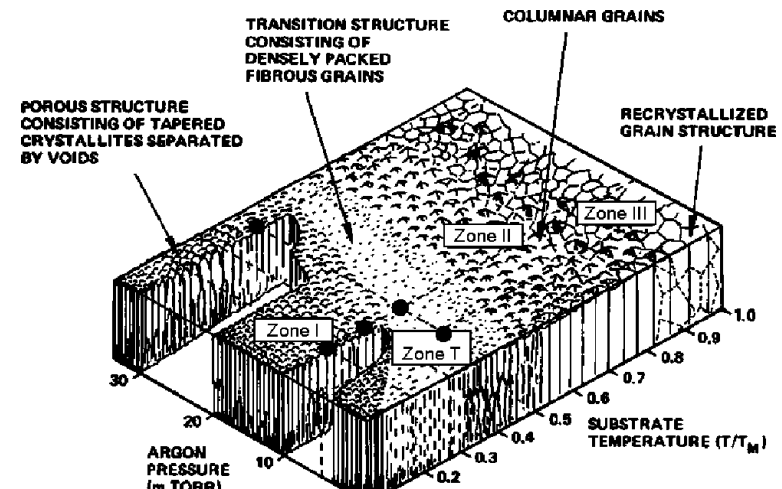


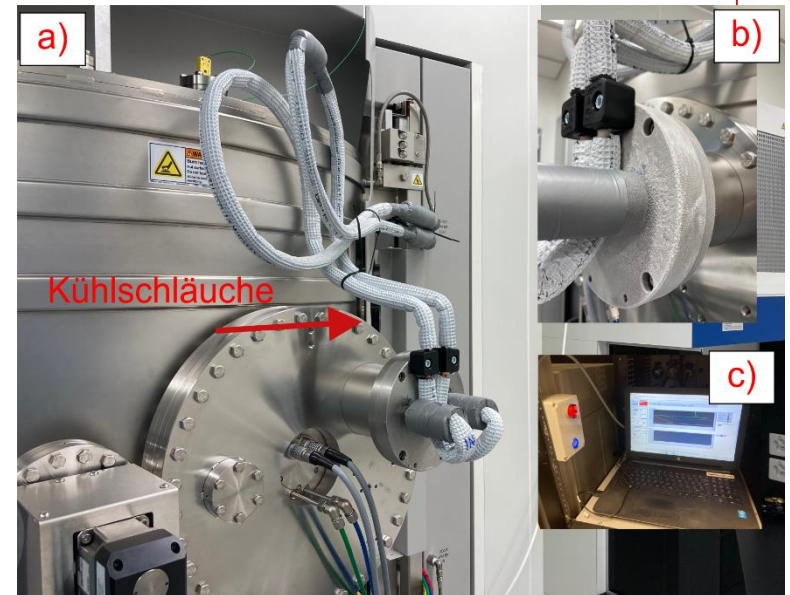
Fig.: Thornton structure zone model.

Coating tool

- Veeco Spector 1.5 Dual Ion Beam Sputter Tool
- 12" high-speed-fixture
- Cryo-pump system

Cooling System

- Cooling power max.: 350 W
- Cooling liquid: R513A (non-flamable)
- 2 inch customized holder (fix)
- Thermal contact: UHV grease



Coating tool

- Veeco Spector 1.5 Dual Ion Beam Sputter Tool
- 12" high-speed-fixture
- Cryo-pump system

Cooling System

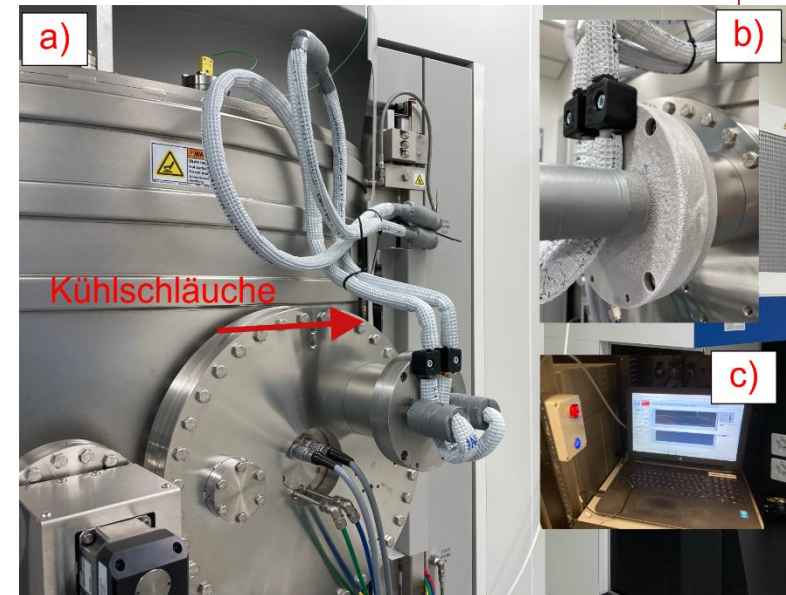
- Cooling power max.: 350 W
- Cooling liquid: R513A (non-flamable)
- 2 inch customized holder (fix)
- Thermal contact: UHV grease

Coating

- Material: SiO_2 , Ta_2O_5
- Coating Temp.: 0°C , 100°C
- Thermal Treatment: $24\text{h}@400^\circ\text{C}$
- Substrates: $\varnothing 25.4 \times 2 \text{ mm}^2$ fused silica; $10 \times 10 \text{ mm}^2$ Si

Thin film characterization:

- n, k: Spectrophotometry PerkinElmer Lambda 1050
- Laser damage resistance: 355 nm, 532 nm, 10 ns, 80 Hz
- Optical losses: cavity ring down (CRD) @638 nm, laser induced deflection (LID) @532 nm



- Temperature distribution:
 - ± 1 K on $\varnothing 2''$

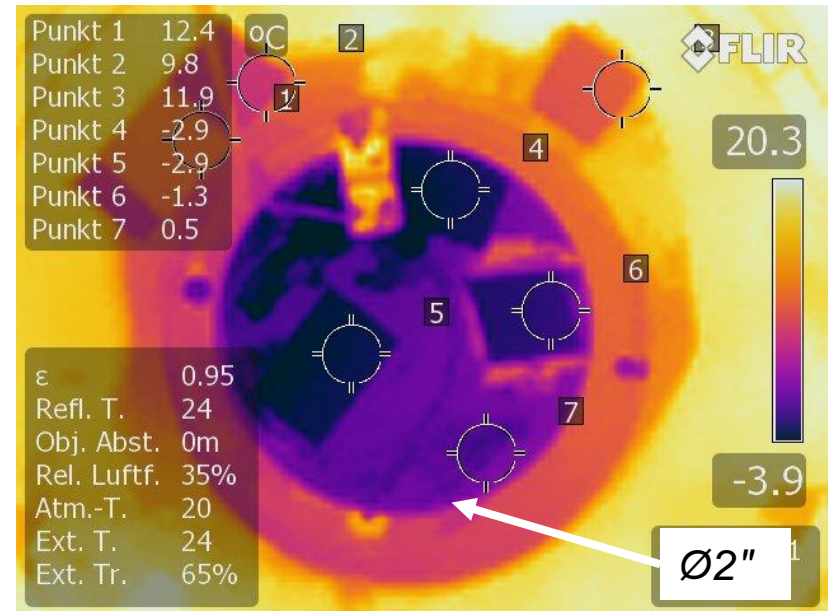


Fig.: Picture of the temperature distribution using a FLIR IR-camera.

Results: Active Cooling

- Temperature distribution:
 - ± 1 K on $\varnothing 2''$
- Minimal achievable temperature on substrate:
 - w/o load: $\approx -10^\circ\text{C}$
 - w load: $\approx 0^\circ\text{C}$
 - $\Delta T \approx 10$ K

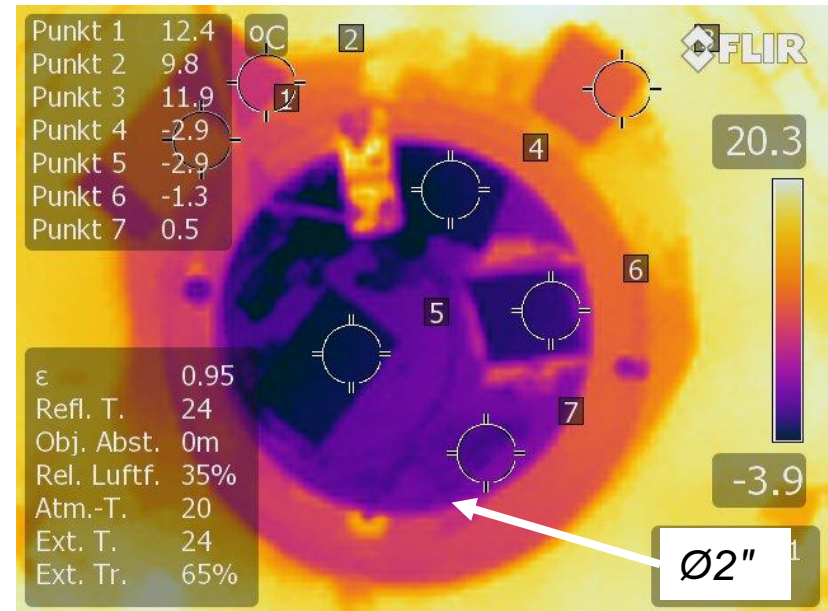


Fig.: Picture of the temperature distribution using a FLIR IR-camera.

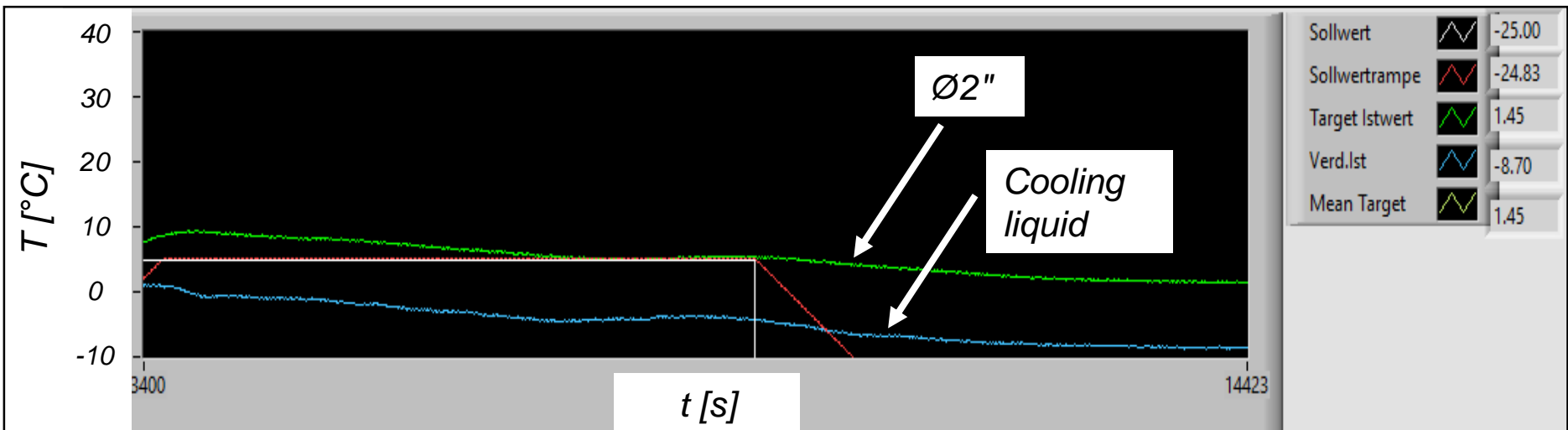


Fig.: Temperature on the substrate and the of the cooling liquid during sputter process.

300 nm single layer, 24h @400°C

- Refractive index @ 500 nm:
 - SiO_2 : ≈ 1.48
 - Ta_2O_5 : ≈ 2.13

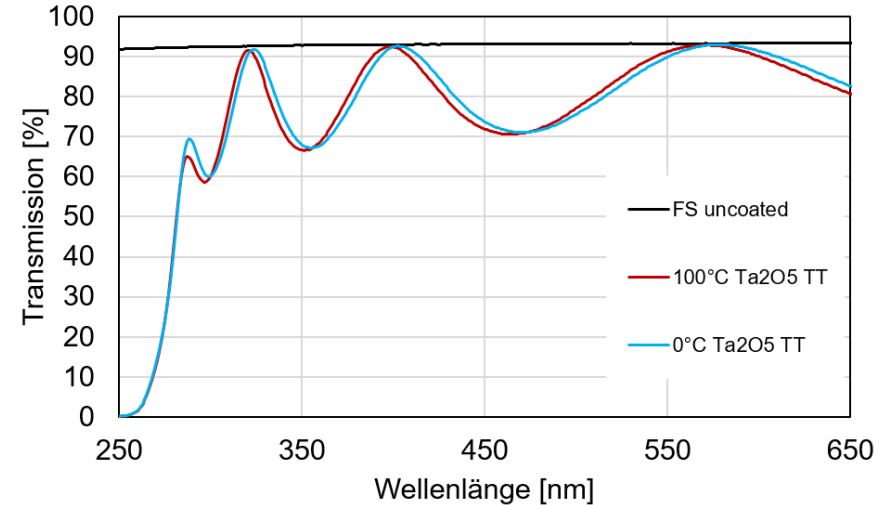


Fig.: Transmission spectra of 300 nm Ta_2O_5 coated at 0°C and 100°C.

Active Cooling

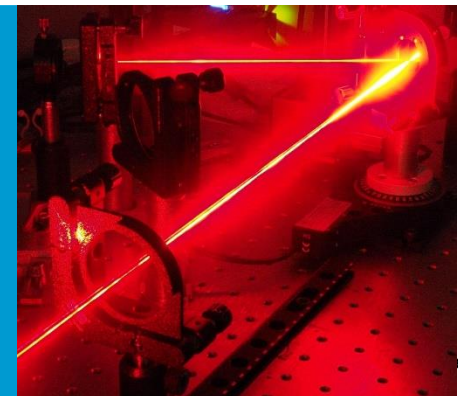
- Controllable temperature down to 0°C
- Reproducible thermal conduct is an issue

Low Temperature Ion Beam Sputter Coatings

- No negative influence on film growth and structure
- “Positive” trend for cold coatings
 - Lower losses
 - Higher LIDT

Dr. Thomas Gischkat
RhySearch, Buchs SG, Switzerland

thomas.gischkat@rhysearch.ch



Active Cooling

- Controllable temperature down to 0°C
- Reproducible thermal conduct is an issue

Low Temperature Ion Beam Sputter Coatings

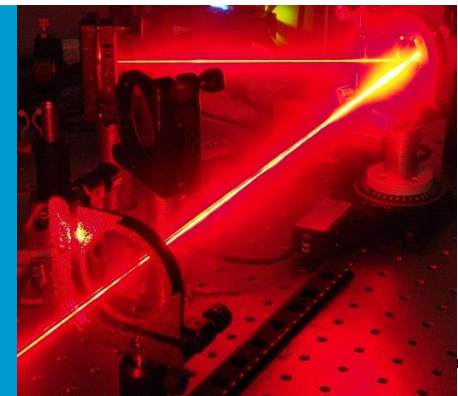
- No negative influence on film growth and structure
- “Positive” trend for cold coatings
 - Lower losses
 - Higher LIDT

➤ **Open Questions:**

- **Only a “optimization“ effect?**
- **What happens to other materials?**
- **What happens at lower temperatures?**

Dr. Thomas Gischkat
RhySearch, Buchs SG, Switzerland

thomas.gischkat@rhysearch.ch



Acknowledgement



Thanks to:

Innosuisse for financial support:



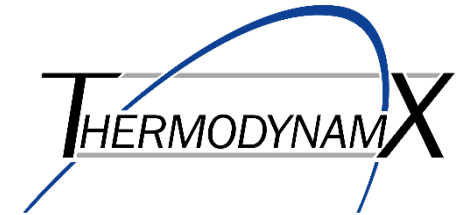
Schweizerische Eidgenossenschaft
Confédération suisse
Confederazione Svizzera
Confederaziun svizra

Innosuisse - Schweizerische Agentur
für Innovationsförderung

47703.1 INNO-ENG

Project-partner:

Bernhard Vetsch
Co-Founder and CTO
ThermodynamX



A special thanks to my co-authors and colleagues at:

IPHT and Fraunhofer IOF:

Dr. Christian Mühlig (LID)



Fraunhofer-Institut für Angewandte
Optik und Feinmechanik IOF

OST Campus Buchs:

Jakob Birkhölzer (XRD)
Tina Strüning



RhySearch:

Daniel Schachtler, Fabian Steger (LIDT, CRD)
Dr. Zoltan Balogh-Michels
Dr. Roelene Botha

